



35.C14023

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TAMAKI KOBAYASHI, ET AL.

Application No.: 09/440,535

Filed: November 16, 1999

For: SUBSTRATE FOR ELECTRON
SOURCE, ELECTRON SOURCE
AND IMAGE FORMING
APPARATUS, AND MANU-
FACTURING METHOD THEREOF

Examiner: A. Patel

Group Art Unit: 2879

July 23, 2001

Commissioner for Patents
Washington, D.C. 20231

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TECHNOLOGY CENTER 2800

RESPONSE TO RESTRICTION REQUIREMENT
AND
PETITION FOR EXTENSION OF TIME

Sir:

Please extend the time for response to the Office Action of May 22, 2001, to Sunday, July 22, 2001. A check in payment of the \$110.00 fee is enclosed. Please charge any additional fee and credit any overpayment to our Deposit Account 06-1205.

In response to the Office Action dated May 22, 2001, Applicants elect, without traverse, to proceed initially with examination of Group I (Claims 1-22).

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110.00 DP

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231 on July 23, 2001.

(Date of Deposit)

FRANK A. DeLUCIA

(Name of Attorney for Applicant)

Signature

July 23, 2001

Date of Signature

Applicants respectfully request favorable consideration on the merits and early passage to issue of the elected claims.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100 or by facsimile at (212) 218-2200. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicants

Registration No. 42,976

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